ISSYS Awarded New Patent for a New Lower Cost Method of Making Microtubes and Flow and Density Meters Associated with This Technology

YPSILANTI, MI--(February 4, 2009) - Integrated Sensing Systems, Inc. (ISSYS) announced that the U.S. Patent Office has granted it a utility patent (US 7,381,628) titled "Process of Making a Microtube and Microfluidic Devices Formed Therewith."

Dr. Nader Najafi, ISSYS President and CEO, stated that, "This new patent and technology offers an improved method of manufacturing micromachined tubes and fluidic sensors. This technology is already seeing use in industrial and biomedical devices, as well as fuel cell systems. This reinforces the other ISSYS' patents on the design, packaging, fabrication, and application of microtube-based sensors, giving ISSYS comprehensive IP protection and offering a competitive barrier to market entry."

According to Doug Sparks, Executive VP of ISSYS, this patent describes a new design and method of forming micromachined tubes used by ISSYS to produce Coriolis mass flow meters, density and chemical concentration sensors, drug infusion systems, fuel cell concentration sensors, and other devices that employ microtube technology. It complements other patents owned by ISSYS in the area of flow sensors and MEMS devices. It provides novel techniques to make larger microtubes for higher flow applications. The new fabrication methods also reduce the cost of manufacturing these micromachined devices by allowing lower cost wafers and materials to be employed. This cost reduction in particular is of paramount importance for high-volume applications such as fuel cells, aviation fuel quality and drug delivery systems or any applications with disposable sensing parts.

Company Background:

ISSYS is a leader in advanced MEMS technologies for industrial, medical devices, microfluidic and scientific analytical sensing applications. Founded in 1995, ISSYS is one of the oldest independent MEMS companies in the US. ISSYS operates a "full manufacturing under one roof," multi-million-dollar, state-of-the-art MEMS fabrication facility located near Ann Arbor, Michigan. An ISO 9001:2000 certified and ISO 13485:2003 (medical device manufacturing) qualified organization, ISSYS is a vertically integrated company dedicated to developing and manufacturing system-level products based on MEMS technology (MEMS Inside), please visit:http://www.mems-issys.com/

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